

Post-deposition Catalytic-doping of Microcrystalline Silicon Thin-layer for the Application in Silicon Heterojunction Solar Cell

Yong Liu, Do Yun Kim, Manuel Pomaska, Yael Augarten, Andreas Lambertz,
Florian Lentz, Jan Mock and Kaining Ding

IEK5-Photovoltaik, Forschungszentrum Jülich

Research Center Jülich

Finance

- Budget: 525 Mio. €
- Third Party: ~ 191 Mio. €

Personnel

- Staff: 5.800
- scientists: 2.074 (incl. PhDs)
+ 907 guest scientists from
more than 45 countries

Scientific Output

- 8.500 patents
- 192 licenses
- 1.800 articles/year



Research Area

- Energy and Climate
- Health
- Information Technology



IEK5-Photovoltaics

Staff: 120

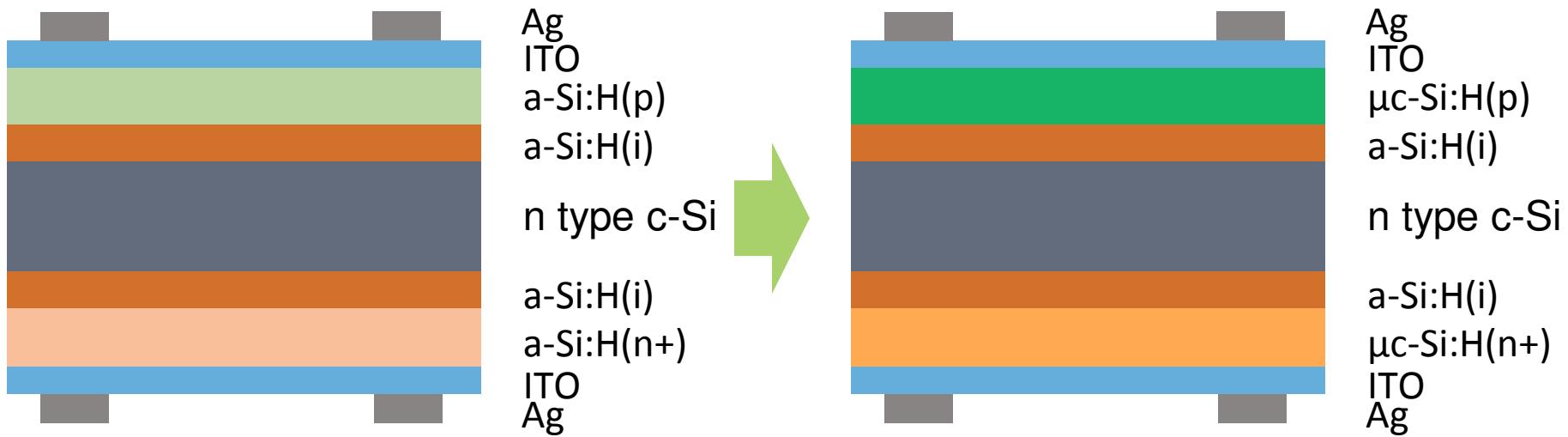
Scientists: ~25

Students : ~25

- **Thin-film technology for silicon wafer solar cells**
- Si thin-film solar cell application platform
- Novel thin-film materials and concepts
- Thin-film analytics and modeling

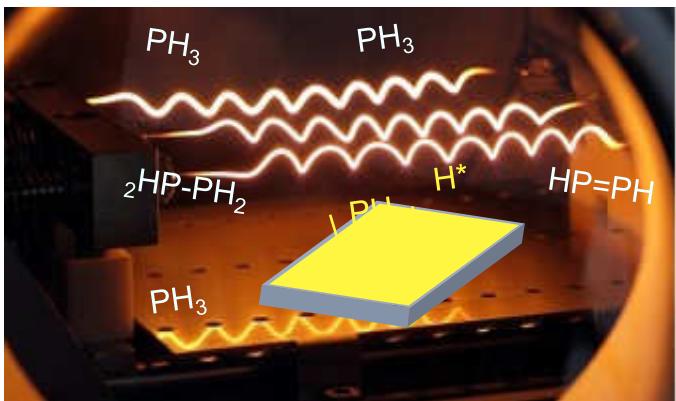


Silicon Heterojunction (SHJ) Solar Cell

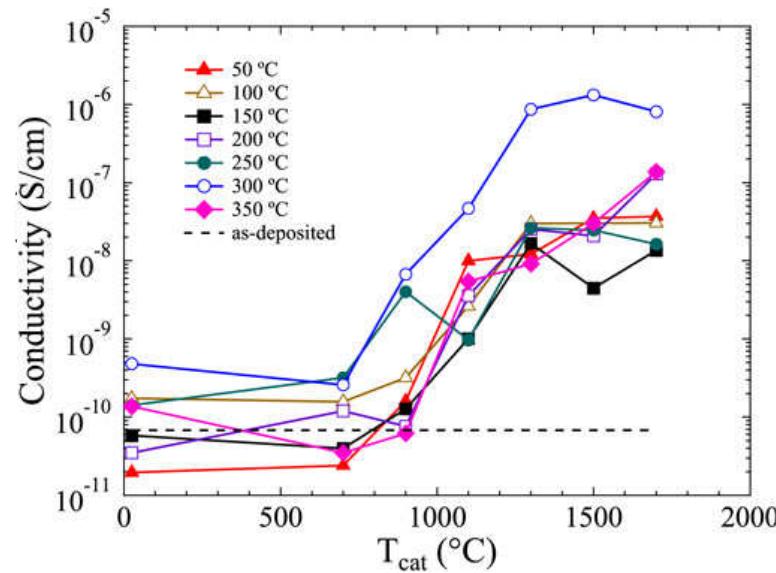


- High V_{OC} due to excellent surface passivation
- Simple, low temperature and up-scalable processes for industrial production
- Compatible with thin wafer process
- $\mu\text{c-Si:H} \rightarrow FF \uparrow$
- rear emitter $\rightarrow J_{SC} \uparrow$
- a-Si:H passivation $\rightarrow V_{OC} \uparrow$
- Efficiency \uparrow

Cat-doping in μ c-Si:H SHJ Solar Cell



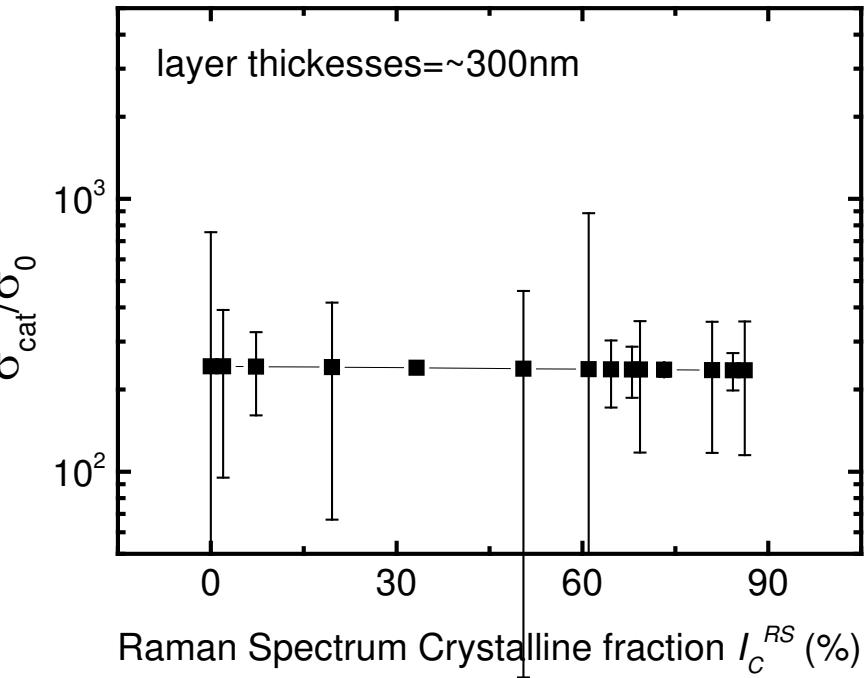
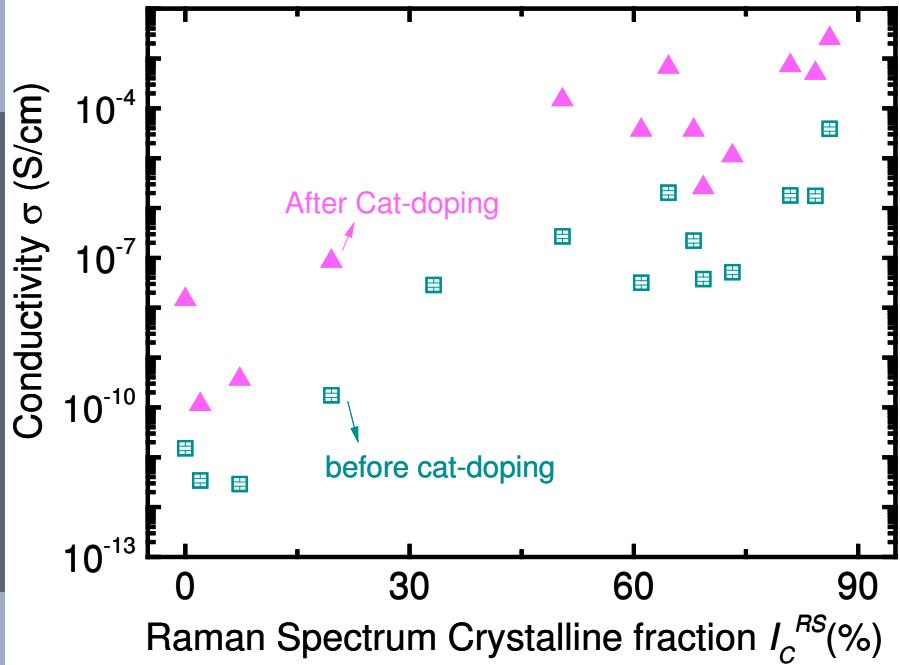
- Low temperature
- Shallow doping depth
- Type conversion
- Improve lifetime by field effect/ H atoms
- Increase conductivity by post-doping
- Compatible with IBC solar cell process



S. Tsuzaki et al., *Jpn. J. Appl. Phys.* 54, 072301 (2015)
J. Seto et al., *Jpn. J. Appl. Phys.* 55, 04ES05 (2016)

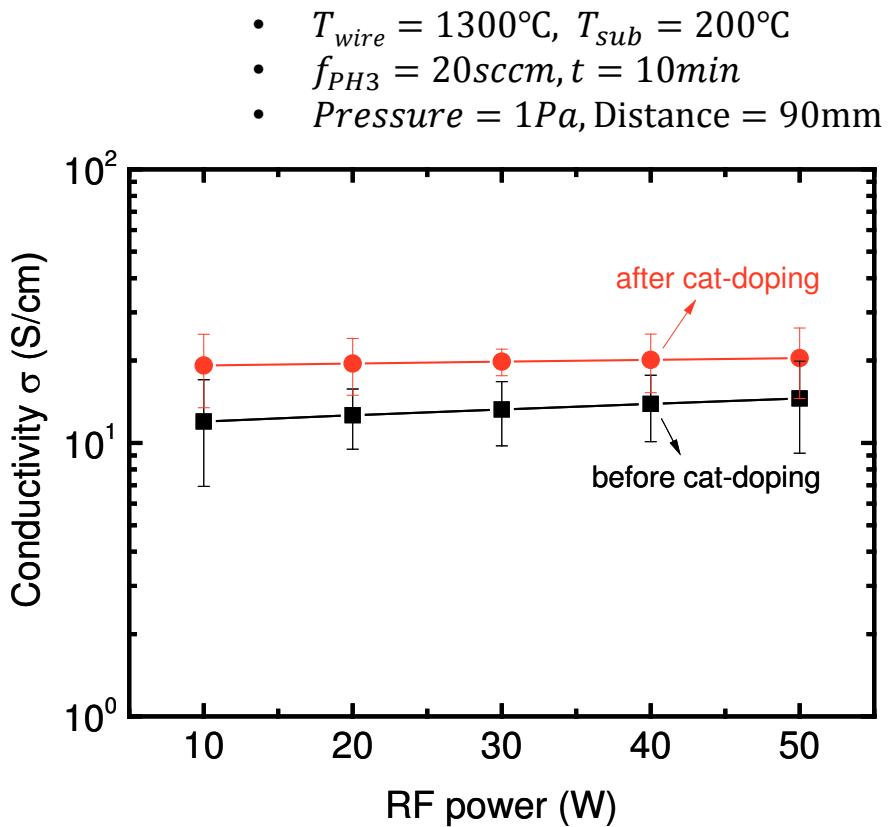
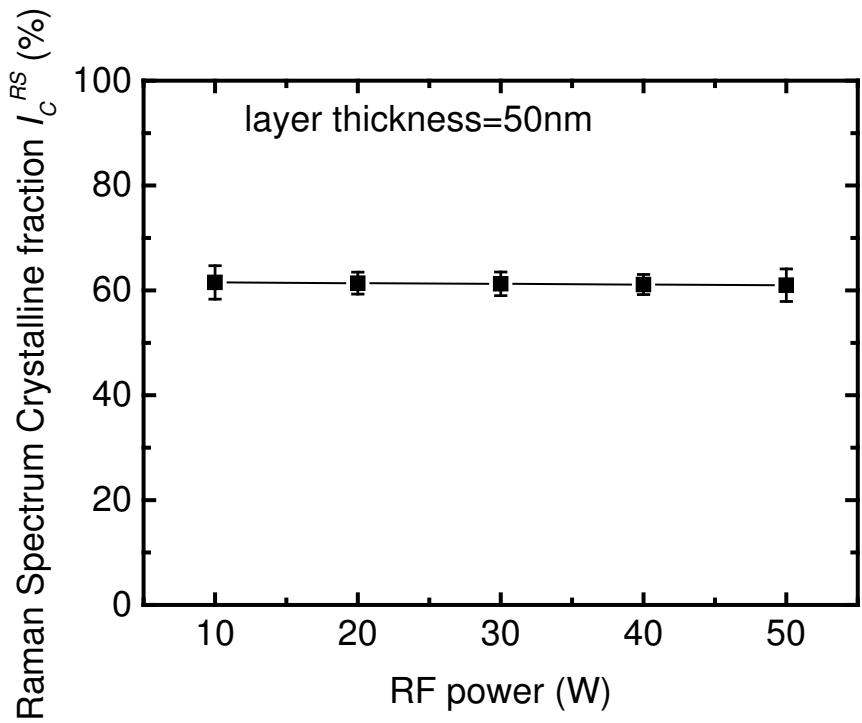
Cat-doping on μ c-Si:H(i)

- $T_{wire} = 1300^{\circ}\text{C}$, $T_{sub} = 150^{\circ}\text{C}$
- $f_{PH_3} = 20\text{sccm}$, $t = 10\text{min}$
- Pressure = 1Pa, Distance = 90mm



- Cat-doping \rightarrow Conductivity \uparrow
- Considering the doping depth, several orders of magnitude's improvement

Cat-doping on μ c-Si:H(n)

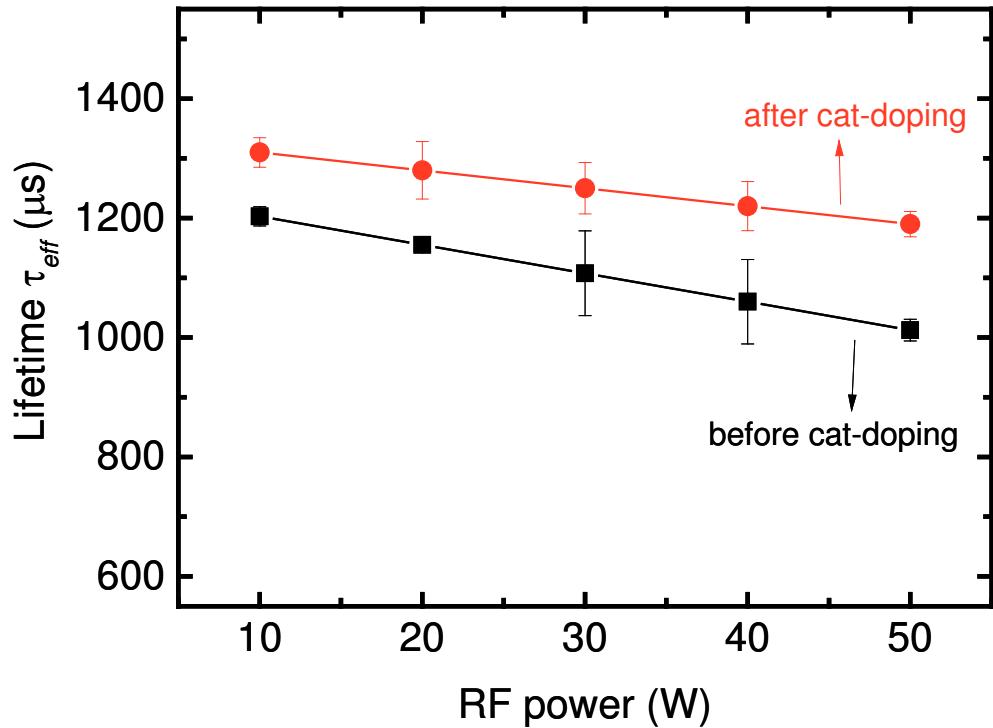


- Crystallinity stayed in a small range though the RF powers changed in a big range

- Conductivity slightly increased after Cat-doping

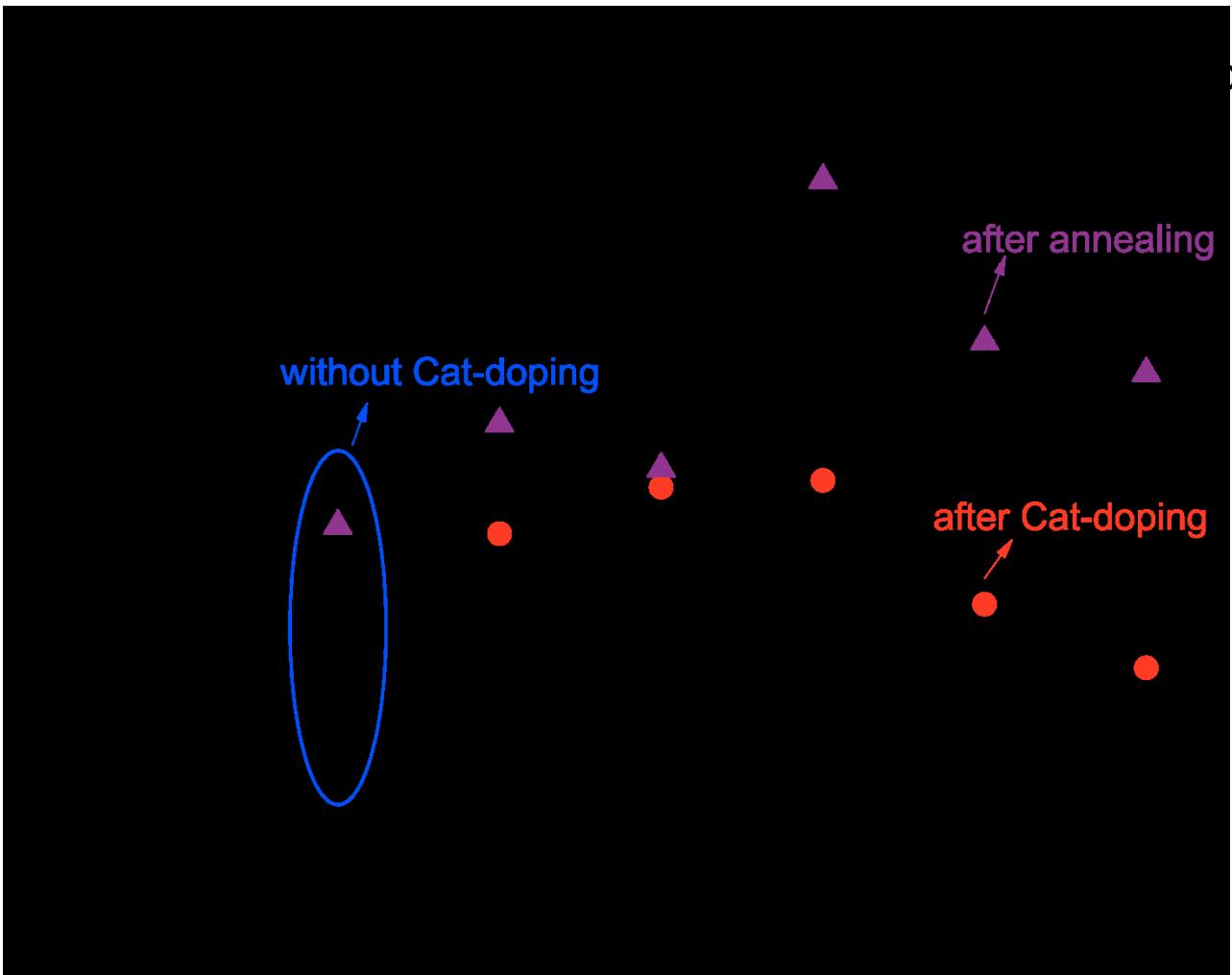
Cat-doping of μ c-Si:H(n) on wafers

- $T_{wire} = 1300^\circ\text{C}, T_{sub} = 200^\circ\text{C}$
- $f_{PH_3} = 20\text{sccm}, t = 10\text{min}$
- Pressure = 1Pa, Distance = 90mm



- Lifetime decreases with increasing RF power probably due to ion bombardment effect
- Lifetime improved after CAT-doping probably due to the field induced passivation

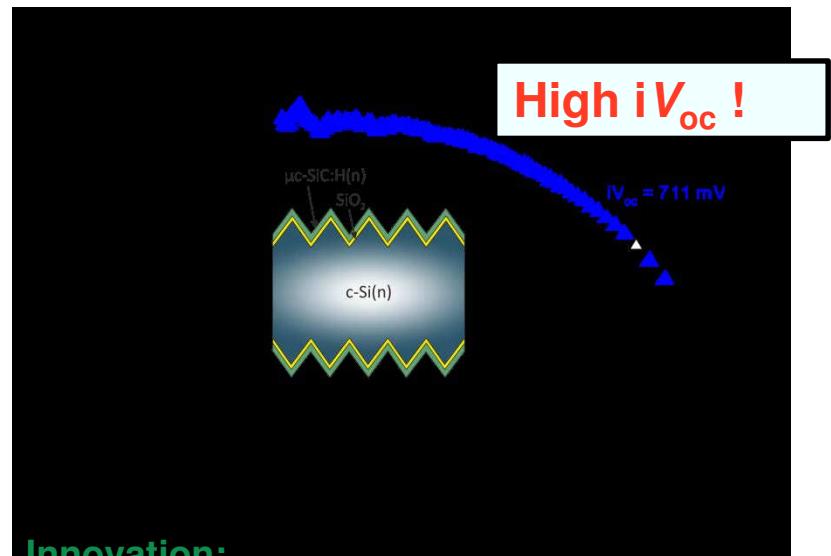
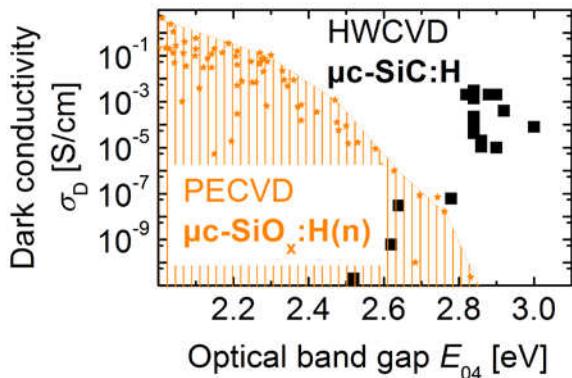
Cat-doping with different T_{wire}



- Cat-doping can improve lifetime by field effect
- After annealing, more P atoms are activated

- $T_{sub} = 200^\circ\text{C}$
- $f_{PH_3} = 20\text{sccm}, t = 10\text{min}$
- Pressure = 1Pa, Distance = 90mm

μ c-SiC:H(n) using HWCVD



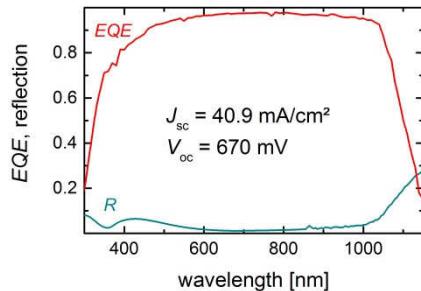
Main material features:

- High transparency (2.6-3.0 eV)
- High refractive index (2.6-3.0)
- High electrical conductivity (up to 14 S/cm)

Classical SHJ solar cell

Ag/ITO/ **μ c-SiC:H(n)**/SiO₂/
c-Si(n)/
a-Si:H(i)/ μ c-SiO_x:H(p)/ITO//

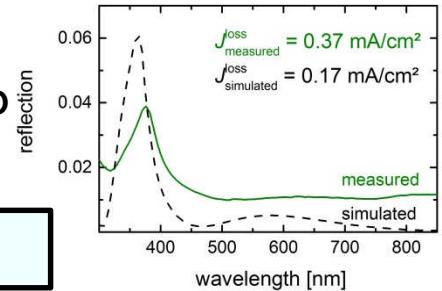
High J_{sc} !



IBC - SHJ solar cell

MgF₂/SiN_x/ **μ c-SiC:H(n)**/SiO
c-Si(n)/
a-Si:H(i)/IBC

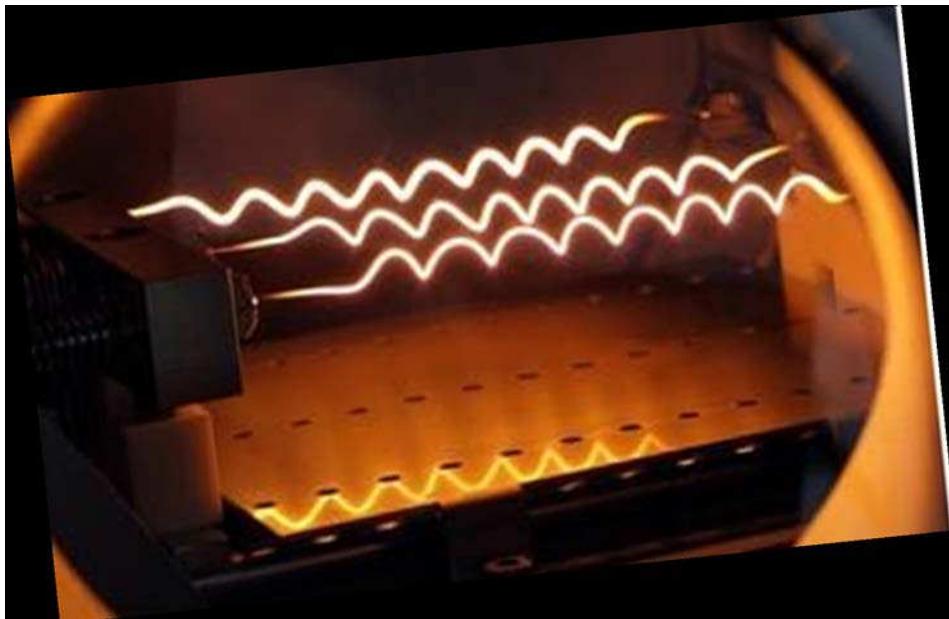
Low reflection !



Summary and Outlook

- Cat-doping can dope both intrinsic and n-type μ c-Si:H
- Cat-doping can improve the τ_{eff} of SHJ solar cell with μ c-Si:H and give the highest τ_{eff} at $900\text{ }^\circ\text{C} \sim 1000\text{ }^\circ\text{C}$
- Annealing can activate the P atoms which leads to further improvement

- P type Cat-doping of μ c-Si:H
- Performance of cell with Cat-doping
- IBC-SHJ solar cell using Cat-doping



Thanks

The Silicon Heterojunction Group:

Scientific Staff: K. Ding, A. Lambertz, D.Y. Kim, F. Lentz, L. Ding, W. Duan, O. Astakhov

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Thank you for your attention!